

Notice of References Cited	Application/Control No. 10/825,394		Applicant(s)/Patent Under Reexamination HARDIKAR, VISHWAS V.	
	Examiner Patricia A. George		Art Unit 1765	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-7,087,564	08-2006	Misra et al.	510/175
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NON-PATENT DOCUMENTS

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.